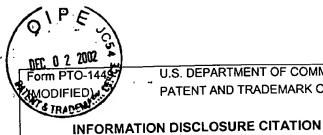
Page 1 of 1 Form PTO-1449 U.S. DEPARTMENT OF COMMERCE ATTY. DOCKET NO. SERIAL NO. (MODIFIED) PATENT AND TRADEMARK OFFICE 039153-0405 (F0945) 09/820,143 APPLICANT INFORMATION DISCLOSURE CITATION Uzodinma Okoroanyanwu et al. **FILING DATE GROUP ART UNIT** (Use several sheets if necessary) 03/28/2001 2878 **U.S. PATENT DOCUMENTS DOCUMENT EXAMINER** FILING DATE SUB-REF DATE CLASS INITIAL IF NUMBER **CLASS** APPROPRIATE M.E. **A1** 6,197,687 3/06/2001 Buvnoski M.E. A2 5,994,225 11/30/99 Liu et al. А3 5,876,903 3/02/99 Ng et al. 5,468,595 A4 11/21/1995 Livesay **FOREIGN PATENT DOCUMENTS** TRANSLATION DOCUMENT SUB-REF DATE COUNTRY CLASS NUMBER CLASS YES NO OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.) Chiong K.G. et al. "Resist Contrast Enhancement in High Resolution Electron Beam Lithography", Journal of W.E **A5** Vacuum Science and Technology: Part B, American Institute of Physics, New York, US, vol. 7, no. 6. Patent Abstracts of Japan, vol 1999, no. 09, 30 July 1999 (1999-07-30) & JP 11 097328 A (Toshiba Corp), 9 M. E. **A**6 April 1999 (1999-04-09) abstract **EXAMINER DATE CONSIDERED** M. El-Shammon 7,25,02 EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include any copy of this form with next

communication to applicant.

Form PTO-1	449	U.S. DEPARTME	NT OF COMMER	RCE	ATTY. DOCKET NO		SERIAL NO	).	<u> </u>	
(MODIFIED PATENT AND TRADEMARK OFFICE			ICE	039153-0405	09/820,143					
/0	4				APPLICANT		1			
/ INF	ORMATI	ON DISCLOSURI	<b>ECITATION</b>		U	zodinma Okoroa	nyanwu et al.			
					FILING DATE		GROUP AF	RT UNIT		
H.	(Use se	everal sheets if nece	essary)		03/28/2	001		2878		
NOV 1 9 7	ALCIK		U.S. PA	ATEN	T DOCUMENTS	14				
EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE		NAME	CLASS	SUB- CLASS			
M.E.	A1	6,232,048	5/15/2001	Buy	noski et al.		7			
M. E.	A2	6,197,687	3/6/01	Buy	noski					
M.E.	А3	6,110,837	8/29/00	Linli	u et al.	The state of the s				
UM.E.	A4	5,876,903	3/2/99	Ng e	et al.				···········	
M.E.	A5	5,468,595	11/21/95	Live	say					
W.E.	A6	3,997,367	12/14/1976	Yau						
			EOPEIGN	DAT	ENT DOCUMENTS					
	1	DOCUMENT	TORLIGIA		EIT DOCUMENTS		0110	TDANS	LATION	
	REF	NUMBER			COUNTRY	CLASS	SUB- CLASS	TRANSLATION YES NO		
	li e			1	***************************************	_1 72-		r 1		
		OTHER DOCL	MENTS (Includ	ina A	uthor, Title, Date, Pe	rtinant Bassa	Eta )			
<u> </u>		OTHER BOCO	INENTS (Includi	ing A	inor, Tille, Dale, Pe	erunent Fayes,	<i>E(C.)</i>			
		· · · · · · · · · · · · · · · · · · ·			<del></del> _	· · · · · · · · · · · · · · · · · · ·	· 			
					•					
		<u> </u>					<u> </u>			
						<u> </u>				
	[		<del></del>	,						
									-	
EXAMINER					DATE CONSIDE	RED			-	
* EXA	MINER:	Initial if citation	considered. w	heth	er or not citation is	s in conforma	nce with M	PEP 609	: Draw	
line	through	citation if not in ion to applicant.	conformance	and	not considered.	nclude any co	ppy of this	form wit	th next	
	<del></del>									



U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE

ATTY. DOCKET NO.

039153-0405 (F0945)

Page 1 of 1 SERIAL NO.

09/820,143

APPLICANT

Uzodinma Okoroanyanwu et al.

**FILING DATE** 

**GROUP ART UNIT** 

(Use several sheets if necessary)

03/28/2001

2878

## U.S. PATENT DOCUMENTS

U.U. TATEN									
EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB- CLASS	FILING DATE IF APPROPRIATE		
CM.E	A1	6,420,097	07/16/2002	Pike et al.	430	313			
ME.	A2	6,395,447	05/28/2002	Ishii et al.	430	191			
CM.2	A3	6,358,670	03/19/2002	Wong et al.	430	296			
M.E.	A4	6,319,655	11/20/2001	Wong et al.	430	311			
M2.	A5	6,200,903	03/13/2001	Oh et al.	438	705			
M. E.	A6	6,174,818	01/16/2201	Tao et al.	438	733			
JW. E.	A7	5,962,195	10/05/1999	Yen et al.	430	316			
- M.E.	A8	4,446,222	05/01/1984	Kress	430	307			
- 4M.E	A9	4394,211	07/19/1983	Uchiyama et al.	156	628			

## **FOREIGN PATENT DOCUMENTS**

REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB- CLASS	YES	NO
	1	_				1	

## OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

	1	

**EXAMINER** 

DATE CONSIDERED

7.25.03

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include any copy of this form with next communication to applicant.

MODIFIED) PATENT AND TRADEMARK OFFICE  O3/18/30-005  PATENT AND TRADEMARK OFFICE  APPLICANT Uzodinma Okoranyanuu et all 03/28/1001  O9/819.342  Shields et al 03/28/2001  O9/819.343  O9/819.344  Osoranyanuu et all 03/28/01  O9/819.344  Osoranyanuu et all 03/28/01  O9/819.352  O9/819.344  Okoroanyanuu et all 03/28/01  O9/819.352  Osoranyanuu et all 03/28/01  O9/819.362  Osoranyanuu et all 03/28/01  O9/819.652  Osoranyanuu et all 03/28/01  O9/819.652  Osoranyanuu et all 03/28/01  Control osoranyanuu et all 03/28/01  Osoranyanuu et all	Form PTO-1	449	U.S. DEPARTME	NT OF COMME	00=	ATTY DOOKET N		<u></u>	<u>Page</u>	<u>1 of 1</u>
### APPLICANT Uzodinma Okoranyanwu et al Several sheets if necessary)  ### U.S. PATENT DOCUMENTS    U.S. PATENT DOCUMENTS   FILING DATE   O3/28/2001   O3/28/01   O3/	· •		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. 039153-0405 (F0945)		SERIAL NO.			
FILING DATE 03/28/2001  Several sheets if necessary)  U.S. PATENT DOCUMENTS  FILING DATE APPROPRIATI 03/28/01 09/819,342 Shields et al	} ·				ADDITIONAL				<u> </u>	
U.S. PATENT DOCUMENTS	PEP	<b>ERMAT</b>	ION DISCLOSURI	CITATION			dinma Okoran	yanwu et	al.	
U.S. PATENT DOCUMENTS	O m	m 2				FILING DATE		GROUP A	RT UNIT	3
DOCUMENT NUMBER   DATE   NAME   CLASS   SUB-   FILING DATE   APPROPRIATI   APPROPRIA	<u> </u>	(US)	several sheets if nece	ssary)		03/28/	2001	7	2878	
DOCUMENT   NUMBER   DATE   NAME   CLASS   SUB-   FILING DATE   FILING DATE   FAPPROPRIATI   Gastriel et al   Golden	9	35 J		U.S. PA	TEN	T DOCUMENTS			900	
Nomber   Shields et al   O9/819,342   Shields et al   O3/28/01	EXAMPLE	REF		DATE		NAME	CLASS			G DATE
O9/819,342   Shields et al   O3/28/01	INTIAL		NUMBER			MAINE	CLASS		1	
O9/819,343			09/819,342		Shie	lds et al			<del> </del>	
Oskoroanyanwu et al	•.		09/819,343		Gabr	iel et al		<del>                                     </del>	<del></del>	
09/819,552   Gabriel et al   03/28/01     09/819,692   Okoroanyanwu et al   438   585     09/81,457   08/15/00   Gabriel   430   318     5,965,461   10/12/99   Yang et al   438   717     5,003,178   03/26/91   Livesay   250   492.300	•		09/819,344		Okor	oanyanwu et al				
09/819,692   Okoroanyanwu et al	• •		09/819,552		Gabr	iel et al		ļ		
6,107,172 08/22/00 Yang et al 438 585 6,103,457 08/15/00 Gabriel 430 318. 5,965,461 10/12/99 Yang et al 438 717 5,003,178 03/26/91 Livesay 250 492.300  FOREIGN PATENT DOCUMENTS  REF DOCUMENT DATE COUNTRY CLASS SUB-CLASS NO TRANSLATION YES NO CLASS (CLASS)  OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)  Livesay, W. R., "Large-area electron-beam source," Journal of Vacuum Science & Technology B, Vol. 11, No. 6, Nov./Dec. 1993, pp. 2304-2308, American Vacuum Society  Yang, J. J. et al, "Electron Beam Processing for Spin-on Polymers and its Applications to Back-End-of-Line (BEOL) Integration," Materials Research Society Symposium Proceedings, Vol. 511, 1998, pp. 49-55, Materials Research Society  Ross et al, "Plasma Etch Characteristics of Electron Beam Processed Photoresist," The Society of Photo-Optical Instrumentation Engineers, Vol. 2438, 1995, pp. 803-816, SPIE-The International Society for Optical Engineering  Grün, Von A. E., "Lumineszenz-photometrische Messungen der Energieabsorption im Strahlungsfeld von Elektronenquellen Eindimensionaler Fall in Luft," Zeitschrift für Naturforschung, Vol. 12a, 1957, pp. 89-95, Publisher: Zeitschrift für Naturforschung; full English Translation attached (11 pgs.)			09/819,692		Okor	oanyanwu et al		<del> </del>	<del> </del>	
5,965,461 10/12/99 Yang et al 438 717 5,003,178 03/26/91 Livesay 250 492.300  FOREIGN PATENT DOCUMENTS  REF DOCUMENT NUMBER DATE COUNTRY CLASS SUB-CLASS NO  OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)  Livesay, W. R., "Large-area electron-beam source," Journal of Vacuum Science & Technology B, Vol. 11, No. 6, Nov./Dec. 1993, pp. 2304-2308, American Vacuum Society  Yang, J. J. et al, "Electron Beam Processing for Spin-on Polymers and its Applications to Back-End-of-Line (BEOL) Integration," Materials Research Society Symposium Proceedings, Vol. 511, 1998, pp. 49-55, Materials Research Society  Ross et al, "Plasma Etch Characteristics of Electron Beam Processed Photoresist," The Society of Photo-Optical Instrumentation Engineers, Vol. 2438, 1995, pp. 803-816, SPIE-The International Society for Optical Engineering  Grün, Von A. E., "Lumineszenz-photometrische Messungen der Energieabsorption im Strahlungsfeld von Elektronenquellen Eindimensionaler Fall in Luft," Zeitschrift für Naturforschung, Vol. 12a, 1957, pp. 89-95, Publisher: Zeitschrift für Naturforschung; full English Translation attached (11 pgs.)			6,107,172	08/22/00	Yang	et al	438	585	<del> </del>	
FOREIGN PATENT DOCUMENTS  REF DOCUMENT DATE COUNTRY CLASS SUB-CLASS NO  OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)  Livesay, W. R., "Large-area electron-beam source," Journal of Vacuum Science & Technology B, Vol. 11, No. 6, Nov./Dec. 1993, pp. 2304-2308, American Vacuum Society  Yang, J. J. et al, "Electron Beam Processing for Spin-on Polymers and its Applications to Back-End-of-Line (BEOL) Integration," Materials Research Society Symposium Proceedings, Vol. 511, 1998, pp. 49-55, Materials Research Society  Ross et al, "Plasma Etch Characteristics of Electron Beam Processed Photoresist," The Society of Photo-Optical Instrumentation Engineers, Vol. 2438, 1995, pp. 803-816, SPIE-The International Society for Optical Engineering  Grün, Von A. E., "Lumineszenz-photometrische Messungen der Energieabsorption im Strahlungsfeld von Elektronenquellen Eindimensionaler Fall in Luft," Zeitschrift für Naturforschung, Vol. 12a, 1957, pp. 89-95, Publisher: Zeitschrift für Naturforschung; full English Translation attached (11 pgs.)			6,103,457	08/15/00	Gabr	iel	430	318		<del></del>
FOREIGN PATENT DOCUMENTS  REF DOCUMENT DATE COUNTRY CLASS SUB-CLASS NO  OTHER DOCUMENTS (Including Author, Title, Date, Perlinent Pages, Etc.)  Livesay, W. R., "Large-area electron-beam source," Journal of Vacuum Science & Technology B, Vol. 11, No. 6, Nov./Dec. 1993, pp. 2304-2308, American Vacuum Society  Yang, J. J. et al, "Electron Beam Processing for Spin-on Polymers and its Applications to Back-End-of-Line (BEOL) Integration," Materials Research Society Symposium Proceedings, Vol. 511, 1998, pp. 49-55,  Materials Research Society  Ross et al, "Plasma Etch Characteristics of Electron Beam Processed Photoresist," The Society of Photo-Optical Instrumentation Engineers, Vol. 2438, 1995, pp. 803-816, SPIE-The International Society for Optical Engineering  Grün, Von A. E., "Lumineszenz-photometrische Messungen der Energieabsorption im Strahlungsfeld von Elektronenquellen Eindimensionaler Fall in Luft," Zeitschrift für Naturforschung, Vol. 12a, 1957, pp. 89-95, Publisher: Zeitschrift für Naturforschung; full English Translation attached (11 pgs.)			5,965,461	10/12/99	Yang	et al	438	717		
REF DOCUMENT NUMBER DATE COUNTRY CLASS SUB-CLASS YES NO  OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)  Livesay, W. R., "Large-area electron-beam source," Journal of Vacuum Science & Technology B, Vol. 11, No. 6, Nov./Dec. 1993, pp. 2304-2308, American Vacuum Society  Yang, J. J. et al, "Electron Beam Processing for Spin-on Polymers and its Applications to Back-End-of-Line (BEOL) Integration," Materials Research Society Symposium Proceedings, Vol. 511, 1998, pp. 49-55, Materials Research Society  Ross et al, "Plasma Etch Characteristics of Electron Beam Processed Photoresist," The Society of Photo-Optical Instrumentation Engineers, Vol. 2438, 1995, pp. 803-816, SPIE-The International Society for Optical Engineering  Grün, Von A. E., "Lumineszenz-photometrische Messungen der Energieabsorption im Strahlungsfeld von Elektronenquellen Eindimensionaler Fall in Luft," Zeitschrift für Naturforschung, Vol. 12a, 1957, pp. 89-95, Publisher: Zeitschrift für Naturforschung; full English Translation attached (11 pgs.)			5,003,178	03/26/91	Livesay		250	492.300		
REF DOCUMENT NUMBER DATE COUNTRY CLASS SUB-CLASS YES NO  OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)  Livesay, W. R., "Large-area electron-beam source," Journal of Vacuum Science & Technology B, Vol. 11, No. 6, Nov./Dec. 1993, pp. 2304-2308, American Vacuum Society  Yang, J. J. et al, "Electron Beam Processing for Spin-on Polymers and its Applications to Back-End-of-Line (BEOL) Integration," Materials Research Society Symposium Proceedings, Vol. 511, 1998, pp. 49-55, Materials Research Society  Ross et al, "Plasma Etch Characteristics of Electron Beam Processed Photoresist," The Society of Photo-Optical Instrumentation Engineers, Vol. 2438, 1995, pp. 803-816, SPIE-The International Society for Optical Engineering  Grün, Von A. E., "Lumineszenz-photometrische Messungen der Energieabsorption im Strahlungsfeld von Elektronenquellen Eindimensionaler Fall in Luft," Zeitschrift für Naturforschung, Vol. 12a, 1957, pp. 89-95, Publisher: Zeitschrift für Naturforschung; full English Translation attached (11 pgs.)				FOREIGN F	PATE	NT DOCUMENTS	<u>-</u>	<u> </u>		
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)  Livesay, W. R., "Large-area electron-beam source," Journal of Vacuum Science & Technology B, Vol. 11, No. 6, Nov./Dec. 1993, pp. 2304-2308, American Vacuum Society  Yang, J. J. et al, "Electron Beam Processing for Spin-on Polymers and its Applications to Back-End-of-Line (BEOL) Integration," Materials Research Society Symposium Proceedings, Vol. 511, 1998, pp. 49-55, Materials Research Society  Ross et al, "Plasma Etch Characteristics of Electron Beam Processed Photoresist," The Society of Photo-Optical Instrumentation Engineers, Vol. 2438, 1995, pp. 803-816, SPIE-The International Society for Optical Engineering  Grün, Von A. E., "Lumineszenz-photometrische Messungen der Energieabsorption im Strahlungsfeld von Elektronenquellen Eindimensionaler Fall in Luft," Zeitschrift für Naturforschung, Vol. 12a, 1957, pp. 89-95, Publisher: Zeitschrift für Naturforschung; full English Translation attached (11 pgs.)		REF				01.00	SUB-	TRANS	LATION	
Livesay, W. R., "Large-area electron-beam source," Journal of Vacuum Science & Technology B, Vol. 11, No. 6, Nov./Dec. 1993, pp. 2304-2308, American Vacuum Society  Yang, J. J. et al, "Electron Beam Processing for Spin-on Polymers and its Applications to Back-End-of-Line (BEOL) Integration," Materials Research Society Symposium Proceedings, Vol. 511, 1998, pp. 49-55,  Materials Research Society  Ross et al, "Plasma Etch Characteristics of Electron Beam Processed Photoresist," The Society of Photo-Optical Instrumentation Engineers, Vol. 2438, 1995, pp. 803-816, SPIE-The International Society for Optical Engineering  Grün, Von A. E., "Lumineszenz-photometrische Messungen der Energieabsorption im Strahlungsfeld von Elektronenquellen Eindimensionaler Fall in Luft," Zeitschrift für Naturforschung, Vol. 12a, 1957, pp. 89-95, Publisher: Zeitschrift für Naturforschung; full English Translation attached (11 pgs.)		NUMBER		DATE		COUNTRY	CLASS			
Livesay, W. R., "Large-area electron-beam source," Journal of Vacuum Science & Technology B, Vol. 11, No. 6, Nov./Dec. 1993, pp. 2304-2308, American Vacuum Society  Yang, J. J. et al, "Electron Beam Processing for Spin-on Polymers and its Applications to Back-End-of-Line (BEOL) Integration," Materials Research Society Symposium Proceedings, Vol. 511, 1998, pp. 49-55,  Materials Research Society  Ross et al, "Plasma Etch Characteristics of Electron Beam Processed Photoresist," The Society of Photo-Optical Instrumentation Engineers, Vol. 2438, 1995, pp. 803-816, SPIE-The International Society for Optical Engineering  Grün, Von A. E., "Lumineszenz-photometrische Messungen der Energieabsorption im Strahlungsfeld von Elektronenquellen Eindimensionaler Fall in Luft," Zeitschrift für Naturforschung, Vol. 12a, 1957, pp. 89-95, Publisher: Zeitschrift für Naturforschung; full English Translation attached (11 pgs.)										
Livesay, W. R., "Large-area electron-beam source," Journal of Vacuum Science & Technology B, Vol. 11, No. 6, Nov./Dec. 1993, pp. 2304-2308, American Vacuum Society  Yang, J. J. et al, "Electron Beam Processing for Spin-on Polymers and its Applications to Back-End-of-Line (BEOL) Integration," Materials Research Society Symposium Proceedings, Vol. 511, 1998, pp. 49-55,  Materials Research Society  Ross et al, "Plasma Etch Characteristics of Electron Beam Processed Photoresist," The Society of Photo-Optical Instrumentation Engineers, Vol. 2438, 1995, pp. 803-816, SPIE-The International Society for Optical Engineering  Grün, Von A. E., "Lumineszenz-photometrische Messungen der Energieabsorption im Strahlungsfeld von Elektronenquellen Eindimensionaler Fall in Luft," Zeitschrift für Naturforschung, Vol. 12a, 1957, pp. 89-95,  Publisher: Zeitschrift für Naturforschung; full English Translation attached (11 pgs.)										
Livesay, W. R., "Large-area electron-beam source," Journal of Vacuum Science & Technology B, Vol. 11, No. 6, Nov./Dec. 1993, pp. 2304-2308, American Vacuum Society  Yang, J. J. et al, "Electron Beam Processing for Spin-on Polymers and its Applications to Back-End-of-Line (BEOL) Integration," Materials Research Society Symposium Proceedings, Vol. 511, 1998, pp. 49-55,  Materials Research Society  Ross et al, "Plasma Etch Characteristics of Electron Beam Processed Photoresist," The Society of Photo-Optical Instrumentation Engineers, Vol. 2438, 1995, pp. 803-816, SPIE-The International Society for Optical Engineering  Grün, Von A. E., "Lumineszenz-photometrische Messungen der Energieabsorption im Strahlungsfeld von Elektronenquellen Eindimensionaler Fall in Luft," Zeitschrift für Naturforschung, Vol. 12a, 1957, pp. 89-95,  Publisher: Zeitschrift für Naturforschung; full English Translation attached (11 pgs.)			OTHER DOCUM	IENTS (Includin	g Au	thor, Title, Date, Pe	ertinent Pages, I	≣tc.)		
6, Nov./Dec. 1993, pp. 2304-2308, American Vacuum Society  Yang, J. J. et al, "Electron Beam Processing for Spin-on Polymers and its Applications to Back-End-of-Line  (BEOL) Integration," Materials Research Society Symposium Proceedings, Vol. 511, 1998, pp. 49-55,  Materials Research Society  Ross et al, "Plasma Etch Characteristics of Electron Beam Processed Photoresist," The Society of Photo-Optical Instrumentation Engineers, Vol. 2438, 1995, pp. 803-816, SPIE-The International Society for Optical Engineering  Grün, Von A. E., "Lumineszenz-photometrische Messungen der Energieabsorption im Strahlungsfeld von Elektronenquellen Eindimensionaler Fall in Luft," Zeitschrift für Naturforschung, Vol. 12a, 1957, pp. 89-95,  Publisher: Zeitschrift für Naturforschung; full English Translation attached (11 pgs.)									B Vol. 1	1 No
Yang, J. J. et al, "Electron Beam Processing for Spin-on Polymers and its Applications to Back-End-of-Line (BEOL) Integration," Materials Research Society Symposium Proceedings, Vol. 511, 1998, pp. 49-55, Materials Research Society  Ross et al, "Plasma Etch Characteristics of Electron Beam Processed Photoresist," The Society of Photo-Optical Instrumentation Engineers, Vol. 2438, 1995, pp. 803-816, SPIE-The International Society for Optical Engineering  Grün, Von A. E., "Lumineszenz-photometrische Messungen der Energieabsorption im Strahlungsfeld von Elektronenquellen Eindimensionaler Fall in Luft," Zeitschrift für Naturforschung, Vol. 12a, 1957, pp. 89-95, Publisher: Zeitschrift für Naturforschung; full English Translation attached (11 pgs.)			6, Nov./Dec. 1993, p	p. 2304-2308, Am	nerica	n Vacuum Society				-, 110.
(BEOL) Integration," Materials Research Society Symposium Proceedings, Vol. 511, 1998, pp. 49-55,  Materials Research Society  Ross et al, "Plasma Etch Characteristics of Electron Beam Processed Photoresist," The Society of Photo-Optical Instrumentation Engineers, Vol. 2438, 1995, pp. 803-816, SPIE-The International Society for Optical Engineering  Grün, Von A. E., "Lumineszenz-photometrische Messungen der Energieabsorption im Strahlungsfeld von Elektronenquellen Eindimensionaler Fall in Luft," Zeitschrift für Naturforschung, Vol. 12a, 1957, pp. 89-95, Publisher: Zeitschrift für Naturforschung; full English Translation attached (11 pgs.)							ers and its Applica	tions to Bac	k-End-of-l	ine
Materials Research Society  Ross et al, "Plasma Etch Characteristics of Electron Beam Processed Photoresist," The Society of Photo-Optical Instrumentation Engineers, Vol. 2438, 1995, pp. 803-816, SPIE-The International Society for Optical Engineering  Grün, Von A. E., "Lumineszenz-photometrische Messungen der Energieabsorption im Strahlungsfeld von Elektronenquellen Eindimensionaler Fall in Luft," Zeitschrift für Naturforschung, Vol. 12a, 1957, pp. 89-95, Publisher: Zeitschrift für Naturforschung; full English Translation attached (11 pgs.)			(BEOL) Integration,"	Materials Resear	rch S	ociety Symposium Pi	roceedings, Vol. 5	511, 1998, pr	49-55	
Optical Instrumentation Engineers, Vol. 2438, 1995, pp. 803-816, SPIE-The International Society for Optical Engineering  Grün, Von A. E., "Lumineszenz-photometrische Messungen der Energieabsorption im Strahlungsfeld von Elektronenquellen Eindimensionaler Fall in Luft," Zeitschrift für Naturforschung, Vol. 12a, 1957, pp. 89-95,  Publisher: Zeitschrift für Naturforschung; full English Translation attached (11 pgs.)	1									
Optical Instrumentation Engineers, Vol. 2438, 1995, pp. 803-816, SPIE-The International Society for Optical Engineering  Grün, Von A. E., "Lumineszenz-photometrische Messungen der Energieabsorption im Strahlungsfeld von Elektronenquellen Eindimensionaler Fall in Luft," Zeitschrift für Naturforschung, Vol. 12a, 1957, pp. 89-95,  Publisher: Zeitschrift für Naturforschung; full English Translation attached (11 pgs.)	1		Ross et al, <i>"Plasma</i> i	Etch Characteristi	cs of	Electron Beam Proce	essed Photoresis	."The Socie	ty of Phot	0-
Engineering  Grün, Von A. E., "Lumineszenz-photometrische Messungen der Energieabsorption im Strahlungsfeld von  Elektronenquellen Eindimensionaler Fall in Luft," Zeitschrift für Naturforschung, Vol. 12a, 1957, pp. 89-95,  Publisher: Zeitschrift für Naturforschung; full English Translation attached (11 pgs.)										
Elektronenquellen Eindimensionaler Fall in Luft," Zeitschrift für Naturforschung, Vol. 12a, 1957, pp. 89-95,  Publisher: Zeitschrift für Naturforschung; full English Translation attached (11 pgs.)										
Elektronenquellen Eindimensionaler Fall in Luft," Zeitschrift für Naturforschung, Vol. 12a, 1957, pp. 89-95,  Publisher: Zeitschrift für Naturforschung; full English Translation attached (11 pgs.)			Grün, Von A. E., <i>"Lui</i>	nineszenz-photon	netris	che Messungen der	Energieabsorption	n im Strahlur	asfeld vo	n
Publisher: Zeitschrift für Naturforschung; full English Translation attached (11 pgs.)	+									
VAMINED									, ρρ. 03-3	·,
	KAMINER							,		
* EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw		······································	citation if not in c on to applicant.	onformance ar	nd no	ot considered. In	clude any cop	v of this fo	arm with	